

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: ) Group Art Unit: 3742  
Koichiro TANAKA ) Examiner: M. Alexandra Elve  
Serial No. 10/721,075 ) Confirmation No.: 7829  
Filed: November 26, 2003 )  
For: LASER IRRADIATION APPARATUS, )  
LASER IRRADIATION METHOD, )  
AND METHOD FOR )  
MANUFACTURING A )  
SEMICONDUCTOR DEVICE )

**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated February 20, 2009, please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 15 of this paper.